

INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

Docket Number (Optional)

OKI.581

Application Number

10/673,676

Applicant(s)

Suguru SASAKI

Filing Date

September 30, 2003

Group Art Unit

TBA 2851

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
PA	A	6,015,644	01/18/2000	CIRELLI et al.			
PA	B	6,335,130	01/01/2002	CHEN et al.			

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
PA	C	11195592 A	07/21/1999	JAPAN			✓	
PA	D	07037769	02/07/1995	JAPAN			✓	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

PA	E	Chris A. Mack, "Inside PROLITH: A Comprehensive Guide to Optical Lithography Simulation", Finle Technologies, Inc., 1997, pgs. 144-151.

EXAMINER

[Signature]

DATE CONSIDERED

7/19/05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.